

PATENT ABSTRACTS OF JAPAN

(11)Publication number : **11-162808**
 (43)Date of publication of application : **18.06.1999**

(51)Int.Cl. **H01L 21/027**
B05C 11/08
// G03F 7/16

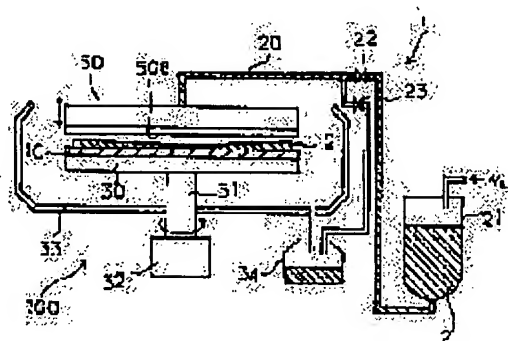
(21)Application number : **09-323261** (71)Applicant : **TOPPAN PRINTING CO LTD**
 (22)Date of filing : **25.11.1997** (72)Inventor : **FUJITA YUICHI**

(54) COATING FLUID SUPPLY APPARATUS FOR SPIN COATING APPARATUS

(57)Abstract:

PROBLEM TO BE SOLVED: To provide a fluid supply apparatus for a spin coating equipment which has excellent uniformity of a coating thickness on a substrate and a limits coating liquid consumption to minimum by a spin coating method, in which a photoresist and the like are coated in manufacturing a color filter for liquid crystal display and the like.

SOLUTION: A slot-extruded coating liquid supply apparatus 1, which discharges curtain-like coating onto a substrate which is spinning slowly, comprises a slotted coating liquid supply head 50 which allows discharge of the coating liquid 2 to continuously increase from the center to the periphery of the substrate 10, a slit width of the head 50 is continuously enlarged from the center to both sides and a slit distance between a manifold provided inside the head 50 and an end 50e of the head is reduced from the center to both ends.



LEGAL STATUS

[Date of request for examination] 10.09.2001

[Date of sending the examiner's decision of rejection]

[Kind of final disposal of application other than the examiner's decision of rejection or application converted registration]

[Date of final disposal for application]

[Patent number]

[Date of registration]

[Number of appeal against examiner's decision of rejection]

[Date of requesting appeal against examiner's decision of rejection]

[Date of extinction of right]